



IFW

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Yasuhiro OMURA et al.

Group Art Unit: 2873

Application No.: 10/525,372

Examiner: M. HASAN

Filed: February 23, 2005

Docket No.: 122800

For: PROJECTION OPTICAL SYSTEM AND METHOD FOR PHOTOLITHOGRAPHY
AND EXPOSURE APPARATUS AND METHOD USING SAME

REQUEST FOR RECONSIDERATION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the February 9, 2007 Office Action, Applicants request reconsideration of this application in view of the following remarks.